Versatile microscope mounts for every application
- High-stability bridge mount ideal for fine structure probing, using programmable 75 mm (3”) X-Y sub-micron transport and 150 mm (6”) linear Z lift (motorized and manual transports also available)
- Large-area bridge mount with 300 mm (12”) X-Y ideal for array and large-area WLR probing

Universal accessory mounting system
- Use with all IV/CV connection panels, vacuum and positioner mounts
- Multiple locations for coax, triax and dual-triax cables
- Fast reconfigurability for multiple test needs

Patented AttoGuard®
- Makes the station invisible to your IV and CV instruments
- <1 fA noise in triaxial IV measurements
- 10 aF resolution CV measurements
- Improved settling time with new thermal isolation

Large-area TopHat™
- Fast setup in <1 minute
- 20% increased working area
- Wide 40 mm RF probe-tip separation
- Optimized for all DC and RF measurement probes

Flexible seals
- Accommodates up to eight low-noise probe positioners
- Large 78 mm2 X-Y microscope adjustment area
- Ensures light-tight and EMI integrity

Quick access control panel for common tasks
- Chuck enclosure ensures moisture-free, light-tight
- EMI-protected measurements, eliminates dark box, making over-temperature measurements easy

Safety load and unload wafers
- Full wafer access via locking roll out stage
- Guarded lift pin option for wafer loading at hot temperatures

Safety interlocks
- X-Y motion control safety interlock
- IV instrument high-voltage safety interlock

Integrated stereo speakers with iPod/MP3 input
- Adjustable platform height for increased user comfort

Velox™ probe station control software
- Intuitive GUI for efficient system utilization by novice and expert users
- Software joystick for precise, sub-micron positioning
- Improved sub-die navigation with CellView
- Easy integration with instrument, testers, and test and measurement software for fast data collection

Powerful automation tools for data collection
- Automatic wafer alignment
- Auto XYZ and theta correction for sub-micron stepping
- Automatic die size measurement tool

Next-generation PureLine™ II
- 10x better spectral noise (≤ - 170dB/Wrms/rtHz)
- 4x better system AC noise (≤ 5 mVp-p)
- Guaranteed shielding effectiveness
- World’s best station for low-level and 1/f measurements

"Hands-free" microscope remote control
- With programmable and motorized transports

Ergonomic accessory mount for system control
- Ergonomic arm rest for easy sub-micron probing

Manual X-Y stage controls
- Automatic MicroChamber air-purge system
- Faster thermal transitions and auto dry-air purge controls for "cold" probing

Patented FemtoGuard® triaxial guarding technology
- ≤ 60˚ C to 300˚ C systems for characterization and modeling
- 400˚ C systems for WLR and power applications
- Stable measurements with thermally optimized platen,
  MicroChamber and ultra-flat wafer chucks

Wide-temperature probing
- Next-generation, semi-automatic stage
- Fast linear motor/air bearing technology (200 mm/sec)
- Super high-accuracy, temperature-compensating design
- Precision wafer stopping and high-force Z stage

Small-footprint, fully integrated system
- Built-in components: motion control, computer controller,
  anti-vibration and air-management systems

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